

# Toward Ultrahigh Efficiency GaN Nano and Micro Full-Color LEDs

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## ABSTRACT

*Using the selective area epitaxy technique, we have demonstrated nanowire emitters with controlled diameter, position, and emission wavelength. Furthermore, monolithic integration of multicolor emission and photonic crystal structure are realized, which allows for ultimately small multicolor nano-LEDs and micro-LEDs with emission properties tailored by the photonic crystal, as well as surface emitting lasers.*

## 1 INTRODUCTION

Micro-light emitting diodes (LEDs) with high brightness and high efficiency in the visible spectrum are critical for a broad range of applications including mobile displays, virtual/mixed/augmented reality devices, bio-sensing, and communications.<sup>1-5</sup> Nevertheless, the realization of high efficiency InGaN micro-LEDs remains a challenge, particularly in the green and red wavelengths. The efficiency of micro-LEDs has been mainly limited by the formation of high defect densities and phase separation upon high indium content, surface non-radiative recombination due to dry-etch induced surface damage and poor current injection.<sup>6-10</sup> The quantum-confined Stark effect due to polarization field further leads to varying emission wavelengths with increasing current.<sup>11, 12</sup>

The fabrication and performance of micro-LEDs by top-down etching has been extensively studied. Jordan et al.<sup>13</sup> revealed a close correlation between the mesa size of micro-LEDs fabricated by top-down approach and peak EQE. A peak EQE of 12-13.5% for blue (455-470 nm) micro-LEDs with a mesa diameter of 2  $\mu\text{m}$  was achieved using wet etching and dielectric passivation by Ryan et al.,<sup>14</sup> which was intended to minimize the surface nonradiative recombination. Neutral-beam-etching technique and regrowth are developed to maintain a similar internal quantum efficiency as unetched quantum wells.<sup>15</sup> Besides top-down approach, bottom-up micro-LEDs and dislocation-free nanostructures have also been studied by us and other groups.<sup>16-20</sup> Using the nanocolumn structure formed by selective area epitaxy (SAE), Hiroto et al.<sup>19</sup> demonstrated monolithic integration of different photoluminescence colors from blue to red and Katsumi et

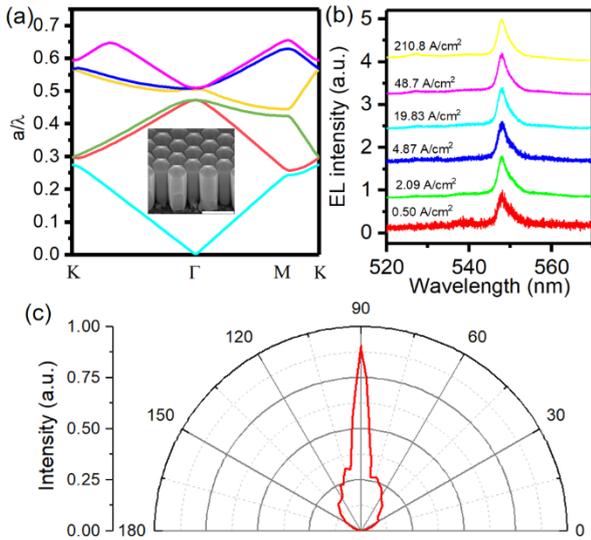
al. further demonstrated multicolor integrated nanocolumn micro-LEDs as a route to micro-LED display.<sup>20</sup> By using a direct epitaxial approach on GaN template with a SiO<sub>2</sub> mask, Jie et al. realized green micro-LED arrays with an external quantum efficiency (EQE) of 6%.<sup>21</sup> Given the advantage in the dislocation-free material quality, the incorporation of indium owing to efficient strain relaxation, and efficient p-type Mg-dopant incorporation, we have performed detailed studies on the epitaxy and properties of nanowire structures and the performance of micro-LEDs.<sup>3, 22-24</sup>

## 2 EXPERIMENT

We use the SAE technique to grow nanowires, which requires the substrate to be patterned prior to growth. First, a 10 nm thick layer of Ti is deposited on a n-GaN-on-sapphire template. This Ti layer serves as the growth mask allowing for growth selectivity. Then electron beam lithography is performed to expose the designed pattern which is usually a triangle lattice of apertures of which the lattice constant and diameter are precisely designed and controlled. The exposed region is developed and subsequently dry etched using resist as the mask to reveal the n-GaN surface in the apertures. Resist stripper is used to remove the resist in a heated bath and thorough solvent clean is performed prior to epitaxial growth.

The epitaxial growth is conducted using a plasma-assisted molecular beam epitaxial system at a relative high temperature after careful tuning of the growth condition. The growth temperature is set sufficiently high to enhance the desorption of Ga adatoms and minimize the growth on Ti surface, while an overly high temperature may lead to a very low, undesirable growth rate. The Ga flux and the nitrogen flow rate are also optimized to minimize unwanted nucleation and growth on Ti surface. Due to the high desorption rate of In, InGaN is typically grown at a considerably reduced temperature under a N-rich condition to allow for In incorporation. By varying the growth temperature, the control over the incorporation of In is readily achieved to allow for different luminescence colors.



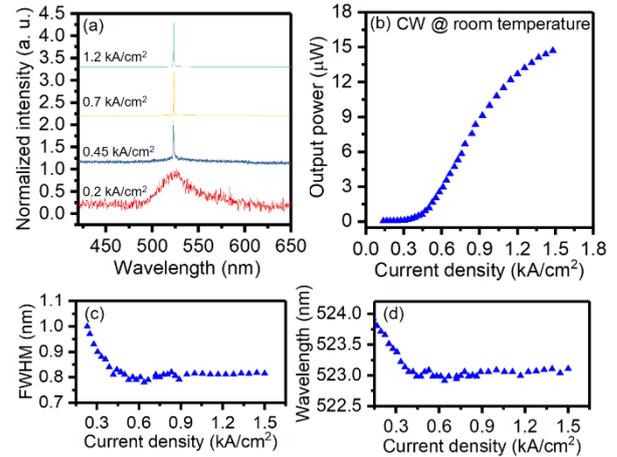


**Fig. 3 (a) Designed photonic bandstructure. The inset is the SEM image of the nanowire photonic crystal where the scale bar represents 500 nm. (b) Electroluminescence spectra of a nanowire photonic crystal micro-LED. (c) The far-field radiation pattern in a 10 nm spectral window at the peak wavelength.<sup>23</sup>**

### 3.4 Surface Emitting Laser Diodes

To date, it has remained challenging to achieve high performance surface emitting laser diodes in the visible or UV spectrum, largely due to the poor quality of GaN-based distributed Bragg reflectors (DBRs). DBR-free surface emitting lasers can be realized by exploiting the optical feedback at  $\Gamma$  point upon introducing optical confinement in the vertical direction. The optical confinement in the vertical direction is realized by the large thickness of low-index GaN cladding layers below and above the active region. In addition, Al is incorporated in the barrier layers in the active region to form an Al-rich shell minimizing the surface nonradiative recombination. The emission spectra are shown in Fig. 4(a).<sup>24</sup> The spectrum has a broad spontaneous peak at  $\sim 524$  nm with a linewidth of  $\sim 30$  nm below threshold. A strong lasing peak with a linewidth of  $\sim 0.8$  nm emerges at  $\sim 523$  nm as the current increases.

Lasing action is confirmed from the nonlinear increase in output power as shown in Fig. 4(b) and simultaneous reduction of spectral linewidths with increasing current as shown in Fig. 4(c) at an injection current of  $400 \text{ A/cm}^2$ .<sup>24</sup> The lasing action remains stable far above the threshold as shown in Fig. 4(d).<sup>24</sup> The threshold current density is much lower than previously reported GaN VCSELs, which is attributed to efficient optical feedback in the photonic crystal and high material quality.<sup>26-28</sup>



**Fig. 4 (a) Emission spectra below and above the threshold. Each spectrum is normalized by its peak intensity. Variations of (b) output intensity, (c) spectral linewidth, and (d) peak wavelength with injection current.<sup>24</sup>**

## 4 CONCLUSIONS

The nanowire structure as a versatile building block has demonstrated its huge potential for light sources suited for various scenarios, including nanoscale high density multicolor emitter arrays, light sources with ultrastable operation and special emission properties, and low threshold coherent light sources. It is expected that the efficiency of nanowire-based light emitters will be significantly improved with further optimization in the epitaxy, device fabrication, and packaging. Moreover, the versatility offered by nanowires holds the promise for meeting the demands of the next generation of lighting and display devices and beyond.

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